

Inventor: Brent A. McClure et al

Title: Capacitor Constructions and Methods of Forming

Assignee: Micron Technology, Inc.

Docket No.: MI22-2067

**INFORMATION DISCLOSURE STATEMENT**

**References – See Attached Form PTO-1449**

The citations listed, copies attached, may be material to the examination of the subject application and are therefore submitted in compliance with the duty of disclosure defined in 37 CFR § 1.56. The Examiner is requested to make these citations of official record in this application. No admission is made regarding whether all the submitted references are prior art.

The materials cited are presented to assist in and expedite examination of this application. The present invention is considered to be patentable over the cited materials. Expeditious examination and allowance of this application as a patent are therefore urged in order that the public may benefit from the disclosure and commercialization of the invention.

Respectfully submitted,

Dated: 21 Jul 2003

Attorney: 

James E. Lake  
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2067	SERIAL NO. Filed Herewith		
<b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				APPLICANT Brent A. McClure et al			
				FILING DATE Filed Herewith	GROUP Unknown		
<b>U.S. PATENT DOCUMENTS</b>							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,180,481	1/01	DeBoer et al			
	AB	6,218,256	4/01	Agarwal			
	AC	6,204,049	8/00	Solayappan			
	AD	6,180,447	1/01	Park			
	AE	6,274,428	8/01	Wu			
	AF	6,124,158	9/00	Dautartas et al			
	AG	6,144,060	11/00	Park			
	AH	5,316,982	5/94	Taniguchi			
	AI	6,281,142	6/99	Basceri et al			
	AJ	6,204,172	9/98	Marsh			
	AK	5,432,732	7/95	Ohmi			
	AL	6,242,299	06/01	Hickert			
<b>FOREIGN PATENT DOCUMENTS</b>							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes      No
	AM						
	AN						
	AO						
	AP						
	AQ						
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	AR		A.W. Ott, et al., "Atomic layer controlled deposition of Al <sub>2</sub> O <sub>3</sub> films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.				
	AS						
EXAMINER		DATE CONSIDERED					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,249,056	06/01	Kwon			
	AB	6,291,289	09/01	Rhodes			
	AC	6,174,770	01/01	Chi			
	AD	5,641,984	06/97	Aftergut et al			
	AE	6,218,260	04/01	Lee et al			
	AF	6,335,240	01/02	Kim et al			
	AG	6,156,606	12/00	Michaelis			
	AH	6,355,519	03/02	Lee			
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	AJ	5,126,283	06/92	Pintchovski et al			
	AK	6,420,230	07/02	Derderian et al			
	AL						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes      No
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	AO						
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	AQ						
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	2001/0024387A1	09/01	Raaijmakers et al				
	AB	2002/0064915A1	05/02	Kitamura				
	AC	2001/0023110A1	09/01	Fukuzumi et al				
	AD	09/653,156		Agarwal (as filed and amended)			08/00	
	AE	09/653,149		Derderian (as filed and amended)			08/00	
	AF							
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	AH							
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